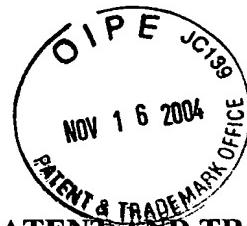


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DOCKET NO.: 2312-0866-2 PCT/smc



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Kimihiro MATSUSE, et al.

SERIAL NUMBER: 09/530,588 GROUP: 2814

FILED: May 5, 2000 EXAMINER: QUACH, TUAN N

FOR: METHOD OF FORMING SEMICONDUCTOR WIRING STRUCTURES

REQUEST TO CORRECT TITLE OF INVENTION

MAIL STOP ISSUE FEE
COMMISSIONER FOR PATENTS
P.O. BOX 1450
ALEXANDRIA, VA 22313-1450

SIR:

In the matter of the above-identified application for patent, we hereby request correction of your records to reflect the correct title of the invention. The title of the invention should read as follows: **METHOD OF FORMING SEMICONDUCTOR WIRING STRUCTURES.**

Respectfully Submitted,

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